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Technology and Application 2014:*

Advanced Display Technology; and Nonimaging Optics: Efficient Design for Illumination and Solar Concentration

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Introduction

We had the great honor of organizing the International Symposium on Optoelectronic Technology and Application 2014 (IPTA 2014) in Beijing. It was truly a great pleasure for us to greet nearly 1,000 participants from many different countries attending IPTA 2014! We firmly believe that the symposium will become an important international event in the field of photoelectronic technology.

IPTA 2014 was sponsored by Chinese Society of Astronautics (CSA) and China High-tech Industrialization Association, technically co-sponsored by SPIE, and organized by Photoelectronic Technology Committee, Chinese Society of Astronautics. 27 cooperating organizations supported the conference. There were nearly 600 papers accepted for presentation at IPTA 2014, contributed by over 1078 authors from more than 10 countries, including United States, United Kingdom, Germany, France, Norway, Australia, Canada, Japan, Korea, Russia, and China. We had six plenary speeches and 228 well-known scientists and experts, from both home and abroad to give invited talks at different sessions.

The purpose of IPTA 2014 was to provide a forum for the participants to report and review innovative ideas, with up-to-date progress and developments, and discuss the novel approaches to application in the field of photoelectronic technology. We sincerely hope that the research and development in the optical and photoelectronic fields will be promoted, and international cooperation sharing the common interest will be enhanced.

On behalf the Organization Committee of IPTA 2014, we would like to heartily thank our sponsors and cooperating organizations for all they have done for the conference. We would also like to thank the authors for their contribution to the proceedings; the participants and friends of IPTA 2014, for their interest and efforts in helping us to make the symposium possible; and the Program Committee for their effective work and valuable advice, especially the IPTA 2014 Secretariat and the SPIE staff, for their tireless efforts and outstanding services in preparing the conference and publishing the Proceedings.

Guofan Jin
Songlin Zhuang
IPTA 2014 Symposium Committee Chairs

